

#### IEEE SW Test Workshop

Semiconductor Wafer Test Workshop

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# Evaluation of New Probe Technology on SnAg and Copper Bumps







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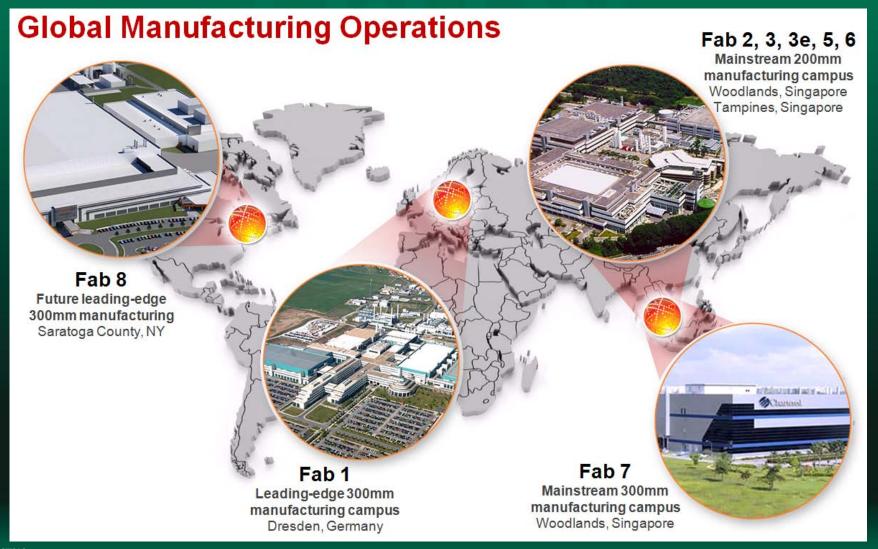
**Darko Hulic (Nikad)** 

#### **Overview**

- Mobile SoC Trends and Experiment Motivations
- Experiment Details
  - Evaluation Parameters
  - Test Vehicle Setup
- Evaluation Results
  - Contact Force vs. Overdrive
  - Probe Marks Comparison
  - Contact Resistance Stability Study
- Future Work
  - 20k Pin Probe Card Characterization
- Summary



#### **GLOBALFOUNDRIES – Who are we?**





# Mobile SoC Trends and Experiment Motivations

Mobile SoC Technology Trends

Mobile SoC IC Trends	Probe Card Design Considerations
Low-power mobile SoC feature INTEGRATION	More Probes per DUT, X000 probes, at smaller pitch (=<130um pitch)
COST-DOWN pressure	Multi-DUT, X8-X16 DUTs
LEAD-FREE to comply with RoHS mandate	SnAg bumps, Copper pillars

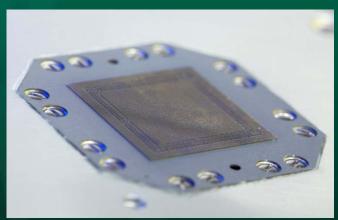
#### Evaluate MicroProbe's Mx Vertical MEMS Technology

- Low-force MEMS probe card to support 20-30k pin cards
- Support SnAg and Copper packaging materials



#### MicroProbe Mx-Flipchip Overview

- Vertical MEMS Architecture
- Multi-DUT capable
- Low probe force: 2-5 g
- Ultra high pin count: >20k
- Application-specific Probe
   Design for advanced packages
  - Optimal Probe Shape for Pitch & Force
  - Specific Metallurgy for Best Contact
  - Replaceable Probes





# **Experiment Details Evaluation Parameters**

- Two Packaging Types
  - SnAg Bumps
  - Copper Pillars

- Two Mx-Flipchip Vertical MEMS Probes
  - Mx-150a: Tip Design 1, Metallurgy 1
  - Mx-150b: Tip Design 2, Metallurgy 2



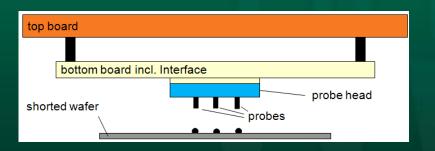






# **Experiment Details** *Test Vehicle Setup*

Two 22-pin test vehicles were used to evaluate Mx technology





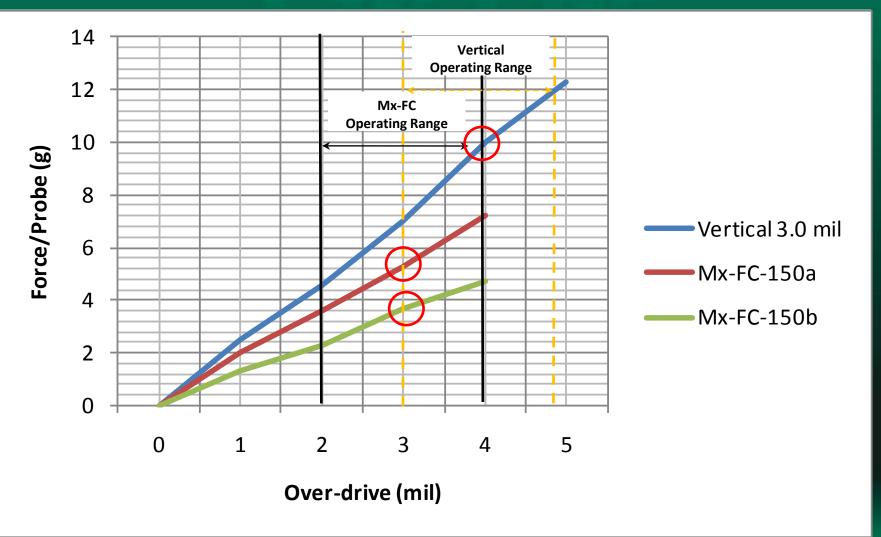
**Probe Layout** 

#### • Test Procedure:

- A defined current is forced and the contact resistance is calculated using the voltage measured
- Probes are triggered in a serial mode and the remaining probes are set to GND
- The measurements have been done on a shorted wafer



# Probe Force vs. Overdrive Mx-FC Probe Force is <50% of Vertical 3.0 mil @ 150um pitch

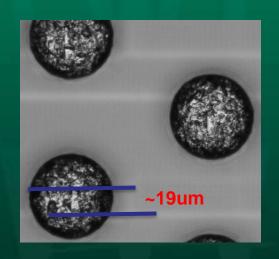




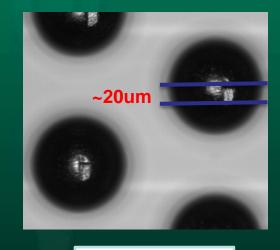
#### **Probe Mark Comparison**



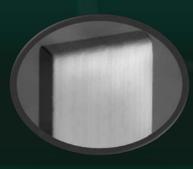
Mx-FC-150a



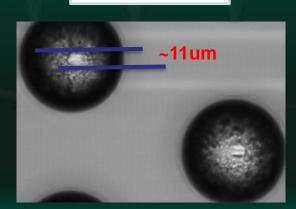
Copper Pillars

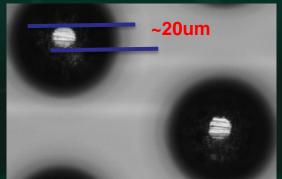


**SnAg Bumps** 



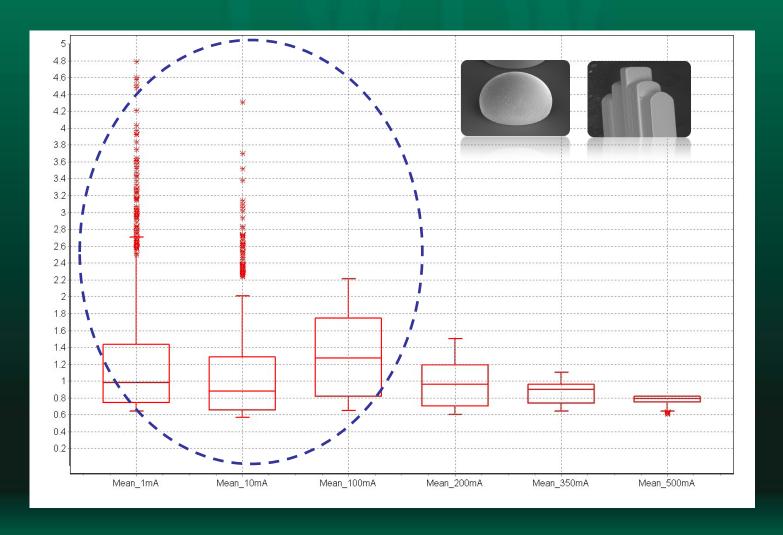
Mx-FC-150b





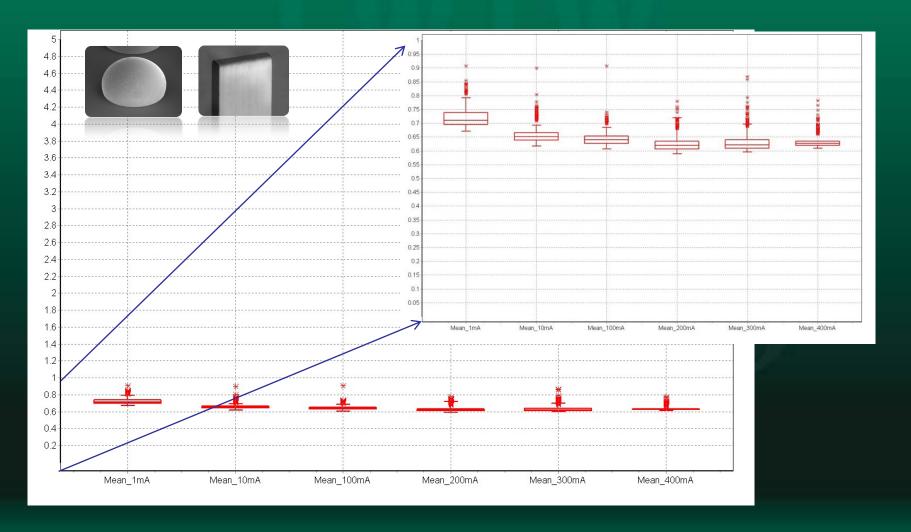


### Mx-FC-150a on SnAg Bumps Contact Resistance Scatters at Lower Currents



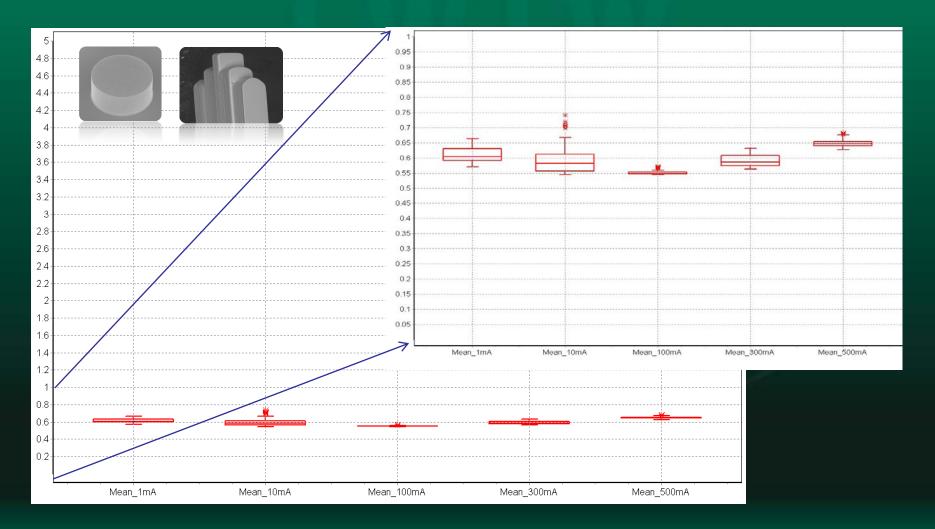


## Mx-FC-150b on SnAg Bumps Stable Contact Resistance Measured At Various Currents



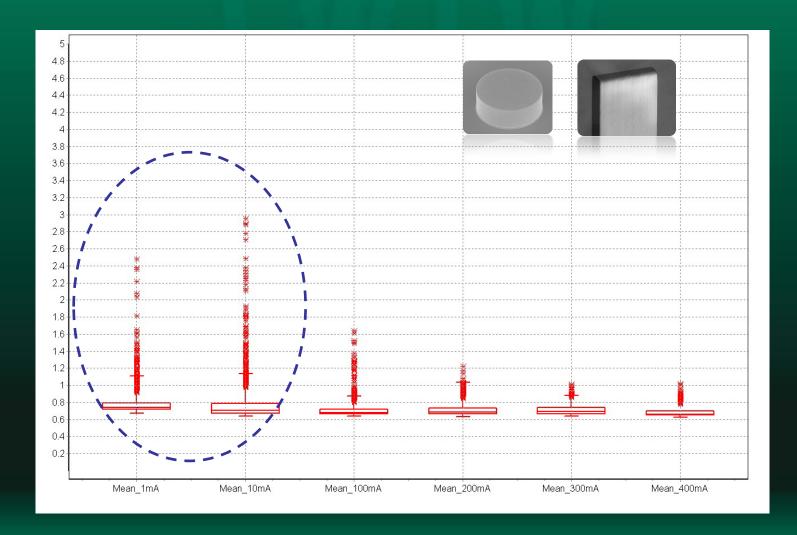


### Mx-FC-150a on Copper Pillar Stable Contact Resistance Measured At Various Currents



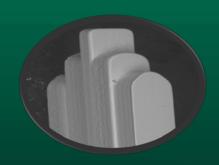


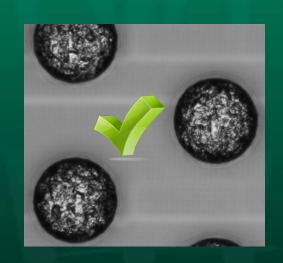
# Mx-FC-150b on Copper Pillars Contact Resistance Scatters at Lower Currents





#### **Optimal Probe Configuration Selected**





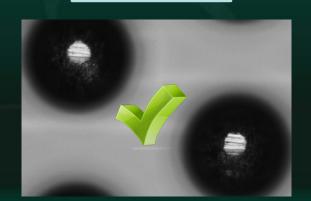
Mx-FC-150a

**Copper Pillars** 

**SnAg Bumps** 



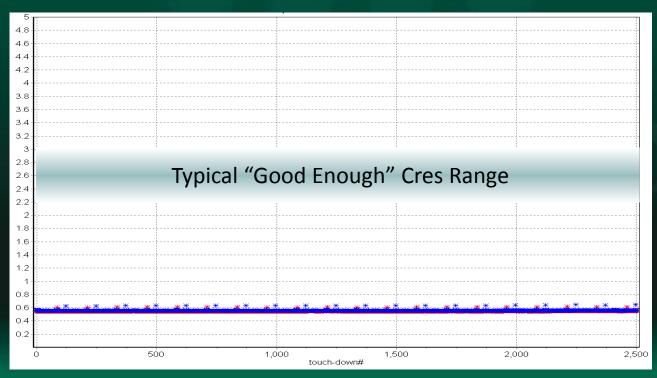
Mx-FC-150b





# Mx-150a on Copper Pillars Stable Contact Resistance over 2500 TD Test

- Current Setting: 100mA
- Cleaning Frequency: 250 TD on-line cleaning
- Cleaning Setting: 25um OD in z-only; 10 TD
- Cleaning Media: 1um lapping film (3M)

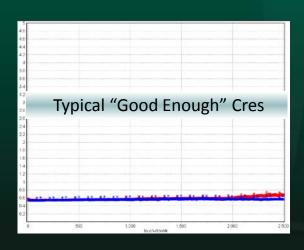




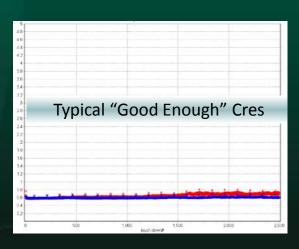
#### Mx-FC-150a on Copper Pillars

Cleaning Recipe can be Further Optimized for Various Currents

- Cleaning Frequency: 250 TD on-line cleaning
- Cleaning Setting: 25um OD in z-only; 10 TD
- Cleaning Media: 1um lapping film (3M)







10mA 100mA 300mA



# Mx-150b on SnAg Bumps Stable Contact Resistance over 2500 TD Test

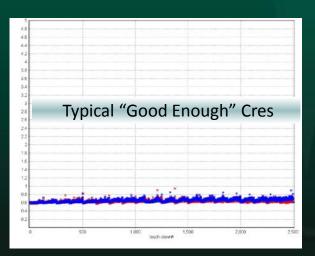
- Current Setting: 100mA
- Cleaning Frequency: 250 TD on-line cleaning
- Cleaning Setting: 25um OD in z-only; 10 TD
- Cleaning Media: 1um lapping film (3M)

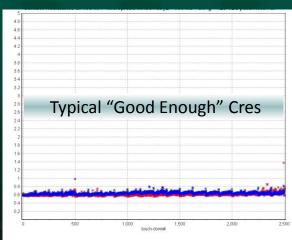


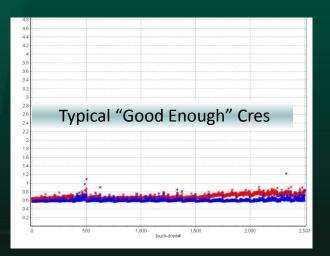


# Mx-FC-150b on SnAg Bumps Stable Cres at Various Current Settings

- Cleaning Frequency: 250 TD on-line cleaning
- Cleaning Setting: 25um OD in z-only; 10 TD
- Cleaning Media: 1um lapping film (3M)





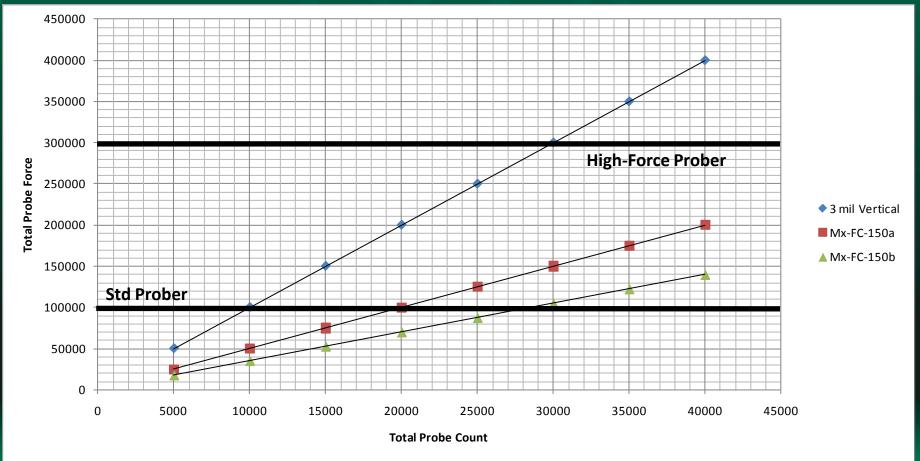


10mA 100mA 300mA



### Future Work: >20k Pin Probe Card Characterization Low Force Mx-FC Probes Enable High Probe Counts and Multi-DUT

 At 100kg limit of a standard prober, low-force Mx-FC-150a and Mx-FC-150b allow maximum probe count of >20,000 probes/card





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### Future Work: >20k Pin Probe Card Characterization Mx shows <50% z-deflection => Better lifetime and product stability

Mx: Vertical MEMS

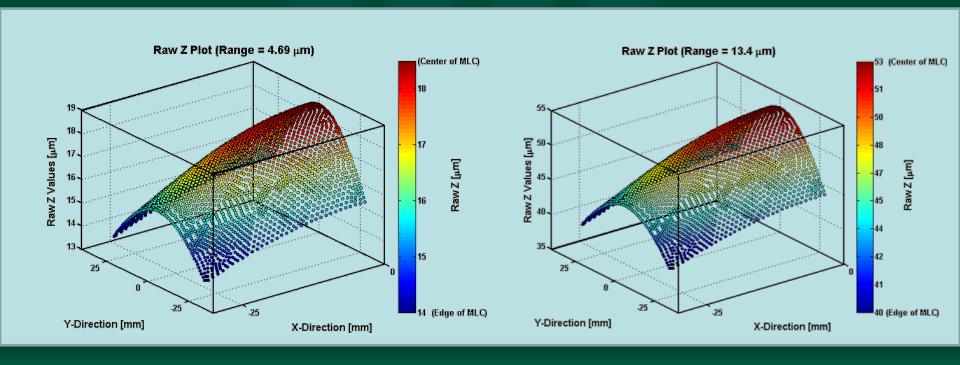
Probe Force = 3.5 g/probe

Z-deflection = 19 um

Cobra-style Vertical

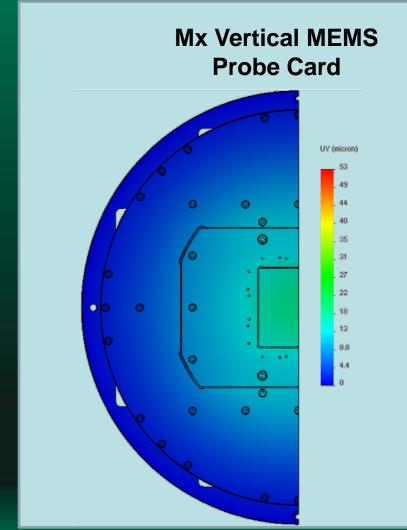
Probe Force = 10 g/probe

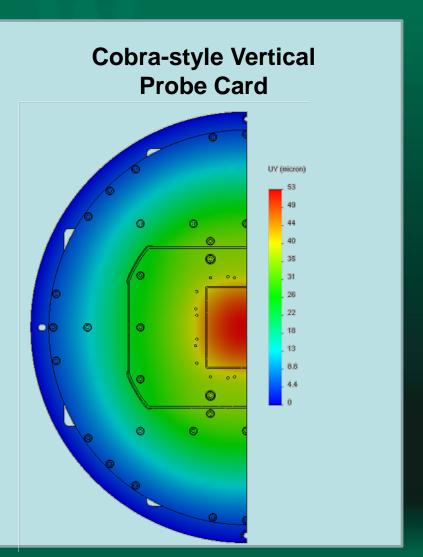
Z-defection = 53 um





### Future Work: >20k Pin Probe Card Characterization Displacement in Probe Load Direction: Mx shows <50% z-deflection







#### Summary

- Freedom to choose metallurgy and probe design allows contact optimization for different bump materials
  - Mx-FC-150a (Tip 1 + PM1) showed good Cres for Cu pillars
  - Mx-FC-150b (Tip 2 + PM2) showed good Cres for SnAg bumps
- Low-force Mx-FC architecture offers scalability in ultra-high pin count and finer pitch
  - At 100kg limit of existing prober install base, Mx-FC enables 20-30k probes
  - Less z-deflection for better probe card lifetime and stability
- Future work
  - >20k pin count probe card performance/lifetime characterization



#### Acknowledgement

#### MicroProbe

- Mike Slessor
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- Rick Marshall

